

WHAT IS CLAIMED IS:

1. A forming method of an ink jet print head substrate in which an ink flow path forming member is attached onto a substrate for forming an ink  
5 discharging pressure generating element, wherein a minute pit is formed on an attachment region of said substrate for attaching said liquid flow path forming member.
- 10 2. The forming method of an ink jet print head substrate according to claim 1, wherein said minute pit is formed by anisotropic etching.
- 15 3. The forming method of an ink jet print head substrate according to claim 2, wherein at least a part of an etching mask for said anisotropic etching is made of polyether amide resin.
- 20 4. The forming method of an ink jet print head substrate according to claim 3, wherein said polyether amide resin layer also serves as an adhering layer between said substrate and said liquid flow path forming member.
- 25 5. An ink jet print head substrate formed by a forming method of an ink jet print head substrate according to any one of claims 1 to 4.

6. A manufacturing method of an ink jet print head using an ink jet print head substrate formed by a forming method of an ink jet print head substrate according to any one of claims 1 to 4, wherein a  
5 discharge port for discharging ink, a liquid path communicating with said discharge port and also including said ink discharging pressure generating element, a liquid flow path forming member attached with said substrate to form said liquid path are  
10 formed on said substrate.

7. The manufacturing method of an ink jet print head according to claim 6, wherein said minute pit is formed in close proximity to both ends of a  
15 longitudinal direction in said ink jet print head.

8. An ink jet print head manufactured by a manufacturing method of an ink jet print head according to claim 6.

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